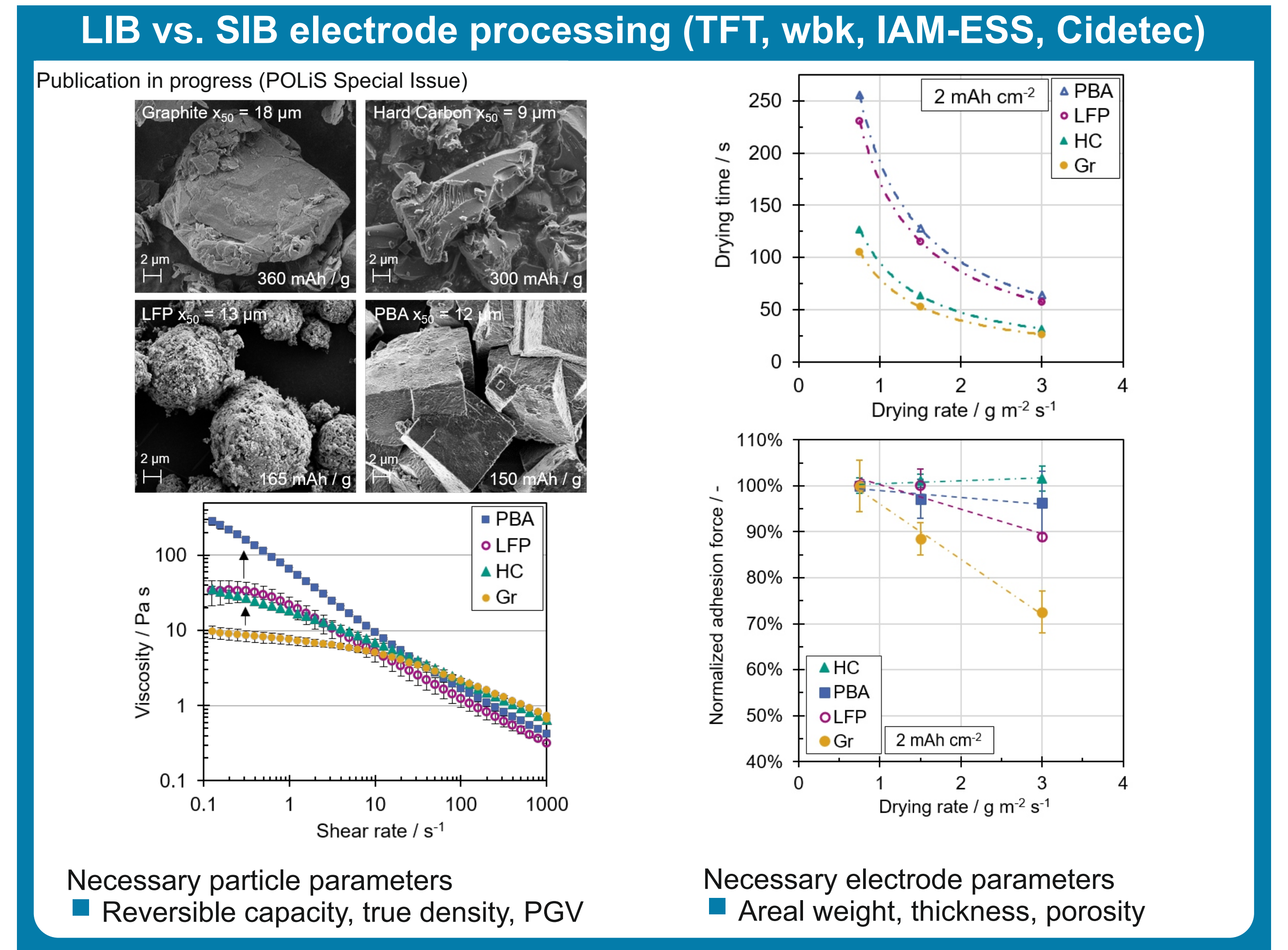
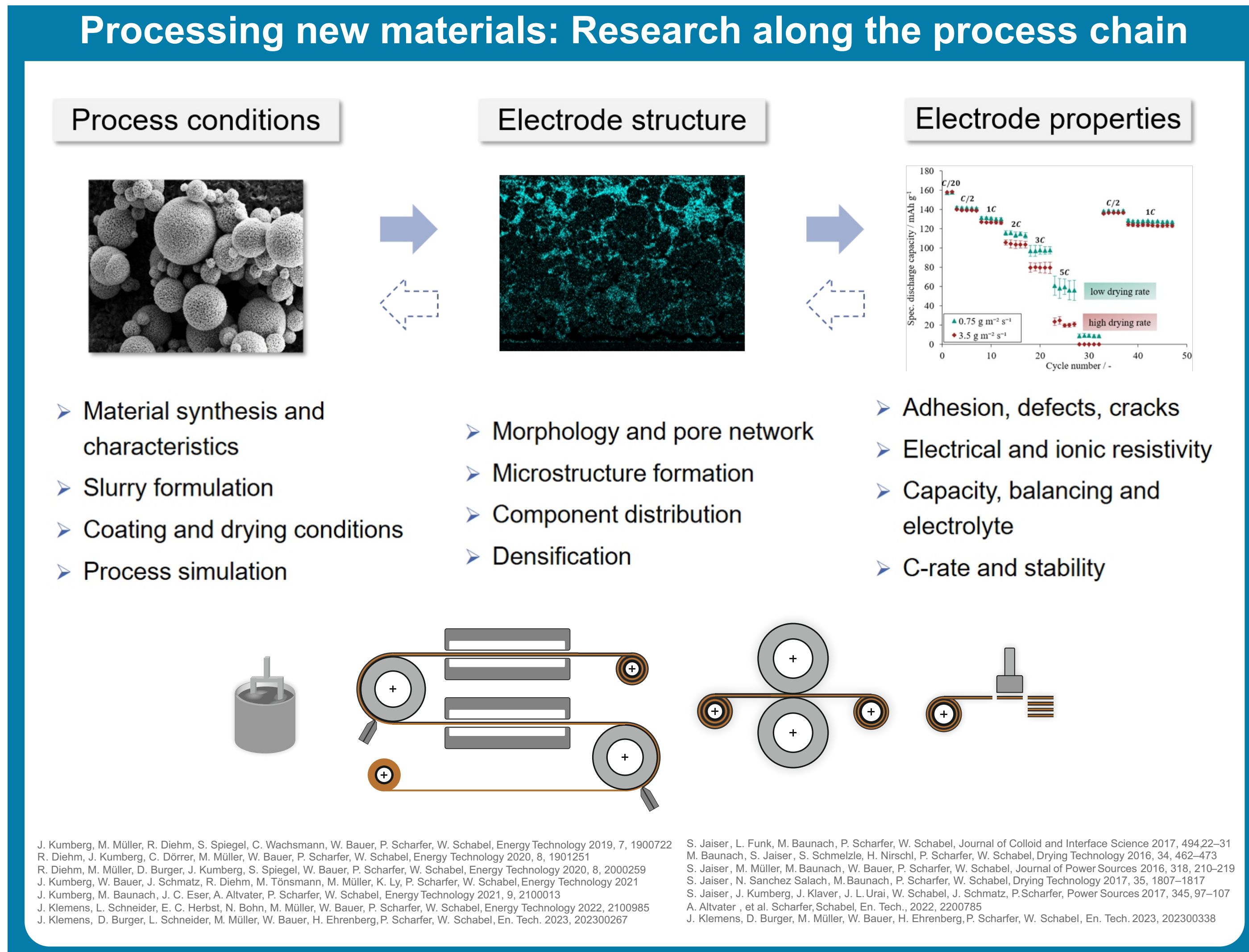


Processing of LIB and SIB Materials with Different Particle Morphology + Microstructure Optimization by Multilayer Architecture

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